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Table of Contents

Light Beam Control	1
Session Chair: M. Selim Unlu <i>Boston University, USA</i>	
Plenary talk: Thomas Bifano MEMS Deformable Mirrors for Wavefront Control <i>Boston University, USA</i>	
Dynamically Deformable Micromirror array for Defined Laser Beam Shaping and Homogenizing	3
J. Masson, R. Bitterli, W. Noell, N.F. de Rooij, A. Bich, K. Weible, R. Voelkel <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i> <i>SUSS MicroOptics, SWITZERLAND</i>	
Fast optical line shaper for ultrashort-pulse laser nanomachining	5
J. Brunne, U. Wallrabe, A. Treffer, M. Bock, R. Grunwald <i>University of Freiburg, GERMANY</i> <i>Max Born Institute, GERMANY</i>	
Sensing Devices and Systems	7
Session Chair: Hiroshi Toshiyoshi <i>University of Tokyo, JAPAN</i>	
Invited presentation 1: Frank Niklaus High-Performance Infrared Micro-Bolometer Arrays Manufactured Using Very Large Scale Heterogeneous Integration	9
F. Forsberg, A.C. Fischer, G. Stemme, N. Roxhed, F. Niklaus, P. Ericsson, B. Samel <i>Royal Institute of Technology, SWEDEN</i> <i>Acreo AB, SWEDEN</i>	
MEMS Fourier Transform IR Spectrometer	11
N.P. Ayerden, S. Holmstrom, H.R. Seren, S. Olcer, J. Sharma, S. Luettjohann, T. Sandner, H. Urey <i>Koç University, TURKEY</i> <i>Bruker Optics, GERMANY</i> <i>Fraunhofer Institute for Photonic Microsystems, GERMANY</i>	
Multi-Wavelength Selective IR emission Using Surface Plasmon Polariton for CO₂ Gas Sensing	13
K. Masuno, T. Sawada, S. Kumagai, M. Sasaki <i>Toyota Technological Institute, JAPAN</i>	
VOA-Based Optical MEMS Accelerometer	15
K. Zandia, J. Zoub, B. Wongb, R.V. Krizeleckyb, Y.-A. Peter <i>Ecole Polytechnique de Montreal, CANADA</i> <i>MPB Communications Inc., CANADA</i>	

Built-in Optical Angular Position Sensing Mechanism for High-Resolution Vibratory Grating Scanner	17
K.K.L. Cheo, G. Zhou, Y. Du, F.S. Chau <i>National University of Singapore, SINGAPORE</i>	
Nanoplasmonics and Aperiodic Structures	19
Session Chair: Thomas Bifano <i>Boston University, USA</i>	
Invited presentation 2: Luca Dal Negro	
Photons in a Labyrinth: Challenges and Opportunities in Aperiodic Nanophotonics	19
<i>Boston University, USA</i>	
Talbot Lithography using Aperiodic Structures	21
H.J. Choi, H. Gao, L. Tian, C.-H. Chang, J.-G. Kim, C.-H. Hsieh, G. Barbastathis <i>Massachusetts Institute of Technology, USA</i> <i>Singapore-MIT Alliance for Research and Technology Centre, SINGAPORE</i>	
Metallo-dielectric Nanopatch Cavity with Extended Metal Shields	23
J.-B. You, W.-J. Lee, K. Yu <i>Korea Advanced Institute of Science and Technology, KOREA</i>	
Angularly Independent Structural Color of Nanostructured Metal Surfaces	25
S.Y. Lee, L. Dal Negro <i>Boston University, USA</i>	
30 nm Metallic Slot Array for Sensing: Theoretical and Experimental Study	27
Q. Tan, A. Cosentino, M. Roussey, H.P. Herzig <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i>	
Scanners and Oscillators	29
Session Chair: Hans Zappe <i>University of Freiburg, GERMANY</i>	
Invited presentation 3: Tobias Kippenberg	
Cavity Optomechanics: Cooling of a Micromechanical Oscillator into the Quantum Regime	31
S. Deleglise, S. Weis, E. Verhagen, E. Gavartin, R. Riviere, A. Schliesser, T. J. Kippenberg <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i> <i>Max-Planck-Institut für Quantenoptik, GERMANY</i>	
Microscanner with Vertical out of Plane Combedrive	33
T. Sandner, D. Jung, D. Kallweit, T. Grasshoff, H. Schenk <i>Fraunhofer Institute for Photonic Microsystems, GERMANY</i>	

A High-Frequency Comb-Actuated Resonant MEMS Scanner for Microdisplays	35
S.K. Gokce, S. Holmstrom, D. Brown, W.O. Davis, H. Urey <i>Koç University, TURKEY</i> <i>Microvision Inc., USA</i>	
MEMS Rotary Stage with Linear Stiffness	37
U. Baran, W.O. Davis, S.Holmstrom, D. Brown, J. Sharma, S.K. Gokce, H. Urey <i>Koç University, TURKEY</i>	
2-Axis MEMS Scanner for a Laser Range Finder	39
I. Aoyagi, K. Shimaoka, S.Kato, W. Makishi, Y. Kawai, S. Tanaka, T. Ono, M. Esashi, K. Hane <i>TOYOTA Central R&D Labs., Inc., JAPAN</i> <i>Tohoku University, JAPAN</i>	
A 2-D Raster Scanning Mirror Driven by Piezoelectric Cantilever Actuator Array in Combinational Mode - Bending and Torsional	41
K.H. Koh, T. Kobayashi, C. Lee <i>National University of Singapore, SINGAPORE</i> <i>National Institute of Advanced Industrial Science and Technology, JAPAN</i>	
Optofluidic Devices and Systems	43
Session Chair: Arda Deniz Yalcinkaya <i>Boğaziçi University, TURKEY</i>	
Invited presentation 4: Jason Heikenfeld	
Electrowetting Optics and Displays: Materials Implications on Performance and Reliability	45
S. Chevalliot, J. Heikenfeld <i>Cincinnati University, USA</i>	
Closed-Loop Pressure Control of an Adaptive Single Chamber Membrane Lens with Integrated Actuation	47
J. Draheim, T. Burger, R. Kamberger, U. Wallrabe <i>University of Freiburg, GERMANY</i>	
Development of Optical Device for Novel Micro Optical Diffusion Sensor	49
T. Oka, K. Itani, Y. Taguchi, Y. Nagasaka <i>Keio University, JAPAN</i>	
Optical Micro-System with Highly Flexible Tunability for Endoscopic Micro-Probes	51
N. Weber, H. Zappe, A. Seifert <i>University of Freiburg, GERMANY</i>	

Micro-Assembly Using Optically Controlled Bubbles	53
W. Hu, K.S. Ishii, A.T. Ohta <i>University of Hawaii, USA</i>	
Nanofabrication Manipulation and Measurement	55
Session Chair: Michal Lipson <i>Cornell University, USA</i>	
Invited presentation 5: Eric Pei-Yu Chiou	
Photothermal Nanoblade for Single Cell Surgery and Large Cargo Delivery	57
T.-H. Wu, T. Teslaa, M.A. Teitell, P.-Y. Chiou <i>UCLA, USA</i>	
Development of Nanometer Scale Temperature Measurement Method with Polarized Near-field Light	59
S. Hosaka, J. Nitta, Y. Taguchi, Y. Nagasaka, T. Saiki <i>Keio University, JAPAN</i>	
A Plastic Lens with Anti-reflective Structures Using a Nanoporous Alumina Template with Lens Curvature	61
Y.-S. Lee, J.-J. Kim, K.-H. Jeong <i>Korea Advanced Institute of Science and Technology, KOREA</i>	
Nanoscale Patterned Sapphire Substrates with Cortex- Like Nanostructures for GaN-Based LEDs	63
Y.-S. Lin, J.A. Yeh <i>National Tsing Hua University, TAIWAN</i>	
Antireflective Subwavelength Gratings on the End Faces of Optical Fibers Fabricated by UV Nanoimprint Lithography	65
Y. Kanamori, M. Okochi, K. Hane <i>Tohoku University, JAPAN</i>	
Optomechanics and Microscopy	67
Session Chair: Hiroshi Miyajima <i>OLYMPUS Corp., JAPAN</i>	
Invited presentation 6: Michal Lipson	
Optomechanics on a Silicon Chip	P IC
<i>Cornell University, USA</i>	
Light propagation mapping in surface waveguides using nano Carbon probe grown on polymer tipped optical fiber	69
Z. Sedaghat, A. Rumyantseva, A. Bruyant, S. Kochtcheev, S. Blaize, S. Jradi, R. Bachelot <i>Universite de Technologie de Troyes, FRANCE</i>	

3-D MEMS Scanning System For Dual-Axis Confocal Microendoscopy	71
J.-W. Jeong, M.J. Mandella, G.S. Kino, C.H. Contag, O. Solgaard <i>Stanford University, USA</i>	
A High Speed MEMS Scanner for 140-kHz SS-OCT	73
K. Isamoto, K. Totsuka, T. Sakai, T. Suzuki, A. Morosawa, C. Chong, H. Fujita, H. Toshiyoshi <i>Santec Corporation, JAPAN</i> <i>University of Tokyo, JAPAN</i>	
MEMS Scanner Based Handheld Imaging Guided Mohs Surgery System	75
Y. Wang, Y. Jang, G. Chao, Q.M. Flemming, M. Raj, K. Bhutani, X. Zhang <i>University of Texas at Austin, USA</i>	
Shutters and Wavelength Selective Devices	77
Session Chair: J. Andrew Yeh <i>National Tsing Hua University, TAIWAN</i>	
Electrostatically Addressable Visored Shutter Array by Electroplating for Astronomical Spectrography	79
T. Takahashi, M. Mita, K. Motohara, N. Kobayashi, H. Fujita, H. Toshiyoshi, N. Kashikawa <i>University of Tokyo, JAPAN</i> <i>National Astronomical Observatory of Japan, JAPAN</i>	
Wavelength Filtering using MEMS Actuated Coupling from Optical Fibres to Spherical Resonators	81
R. Blue, L. Li, G. M. H. Flockhart, D. Uttamchandani <i>University of Strathclyde, UK</i>	
Optical Characterization Of Photonic Crystals As Polarizing Structures For Tunable Optical MEMS Devices	83
R. Zamora, M. Benes, T. Kusserow, H. Hillmer, U. Akcakoca, B. Witzigmann <i>University of Kassel, GERMANY</i>	
A Fabry-Perot refractometer for chemical vapor sensing by solid-phase microextraction	85
R. St-Gelais, G. Mackey, J. Saunders, J. Zhou, A. Leblanc-Hotte, A. Poulin, J.A. Barnes, H.-P. Looock, R. S. Brown, Y.-A. Peter <i>Ecole Polytechnique de Montreal, CANADA</i> <i>Queens University, CANADA</i>	
Energy Harvesting and Data Transmitting Microsystem Using a Light Emitting Diode	87
I. Haydaroglu, S. Mutlu <i>Boğaziçi University, TURKEY</i>	

Nanoscale Integration and Interference Devices

89

Session Chair: Hartmut Hillmer

University of Kassel, GERMANY

Invited presentation 7: Ulrich Rant

Switchable DNA Interfaces.....PIC

Technische Universität München, GERMANY

Precise Control of DNA Orientation for Improved Functionality in Protein Binding Microarrays 91

P. Spuhler, X. Zhang, M. Monroe, J. Greenspun, M.S. Unlu, L. Sola, M. Chiari

Boston University, USA

Italian National Research Council, ITALY

Silicon Subwavelength Gratings for Reflective Color Filters with Wide Viewing Angle 93

T. Ozaki, Y. Kanamori, K. Hane

Tohoku University, JAPAN

Widely Tunable Laser Composed of Compact Polymer Add/Drop Filter Reflector and Reflective Semiconductor Optical Amplifier 95

O.-S. Kwon, Y. Chung

Kwangwoon University, KOREA

Double-Layer Silicon Photonic Crystal Fiber Tip Sensor 97

B. Park, I.W. Jung, J. Provine, G. Shambat, J. Vuckovic, R.T. Howe, O. Solgaard

Stanford University, USA

Argonne National Laboratory, USA

Periodic Nanostructures and Devices

99

Session Chair: Luca Dal Negro

Boston University, USA

Enhanced photonic resonance tuning through coupling of PhC-based triple-beam nanocavities 101

X. Chew, G. Zhou, F.S. Chau

National University of Singapore, SINGAPORE

Tight-Binding Mechanism in Slow Light Regime 103

A.E. Akosman, M. Mutlu, H. Kurt, E.Ozbay

Bilkent University, TURKEY

TOBB University of Economics and Technology, TURKEY

Efficient and Compact Coupling to Slow Light Structures	105
K. Üstün, H. Kurt <i>TOBB University of Economics and Technology, TURKEY</i>	
Dynamical properties of a coupled nonlinear dielectric waveguide surface-plasmon system as a new type of Josephson Junction	107
Y. Ekşioğlu, Ö.E. Müstecaplıoğlu, K. Güven <i>Koç University, TURKEY</i>	
Macroscopic Photoconductive Nanowire Arrays	109
M. Bayindir, M. Yaman, E. Ozgur, O. Aktas, T. Khudiyev, M. Kanik, H. Deniz <i>Bilkent University, TURKEY</i>	
Nanoscale Manipulation and Imaging	111
Session Chair: Ulrich Rant <i>Technische Universität München, GERMANY</i>	
Invited presentation 8: Hatice Altuğ	
Flexible Plasmonics and Metamaterials	P IC
<i>Boston University, USA</i>	
Integrated organic optoelectronic system for refractometric measurements	113
D. Threm, Y. Nazirzadeh, A. Pradana, M. Rädler, J. Mikat, M. Gerken <i>Christian-Albrechts-Universität zu Kiel, GERMANY</i>	
Miniature Photoacoustic Imaging Probe Using MEMS Scanning Micromirror	115
W. Liao, W. Liu, J. Sun, Y. Zhu, L. Wu, H. Xie, L. Xi, H. Jiang <i>University of Florida, USA</i>	
Deformable Nanoplasmonic Membrane for Highly Sensitive Surface-enhanced Raman Spectroscopy	117
M.-H. Kang, J.-J. Kim, and K.-H. Jeong <i>Korea Advanced Institute of Science and Technology, KOREA</i>	
Biosensing	119
Session Chair: David Dickensheets <i>Montana State University, USA</i>	
Interferometric Reflectance Imaging Sensor for Point-of-Care Viral Identification	121
G.G. Daaboul, A. Yurt, C. Lopez, J.H. Connor, B. Goldberg, S Unlu <i>Boston University, USA</i>	
Microdroplet application in protein sensing	123
T.-C. Liao, J.A. Yeh <i>National Tsing Hua University, TAIWAN</i>	

Label-Free Pathogen Sensing: Microarray Studies for Clinical and Research Applications	125
C.A. Lopez, G.G. Daaboul, C. Yu, C.A. Genco, T.W. Geisbert, J.H. Connor, B.B. Goldberg, M.S. Unlu <i>Boston University, USA</i>	
Artificial Olfaction Inside Nanostructured Infrared Fiber Arrays	127
M. Yaman, A. Yildirim, M. Bayindir <i>Bilkent University, TURKEY</i>	
Micromirror Arrays and Gratings	129
Session Chair: Harald Schenk <i>Fraunhofer Institute for Photonic Microsystems, GERMANY</i>	
Addressable MEMS Slit Mask for Multi-Object Spectroscopy Based on Multi-Wafer Stacking	131
M. Canonica, W. Noell, N. de Rooij, F. Zamkotsian, P. Lanzoni <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i> <i>Laboratoire d'Astrophysique de Marseille, FRANCE</i>	
MEMS spatial light modulator for spectral phase and amplitude modulation	133
J. Dunayevsky, D.M. Marom <i>Hebrew University, ISRAEL</i>	
A Dual-Axis High Fill-Factor Micromirror Array for High Thermal Loads	135
Ç. Ataman, S. Lani, W. Noell, F. Jutzi, D. Bayat, and N. de Rooij <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i>	
Microfabrication and Characterization of Fully Programmable Optical MEMS Gratings with Long Low-Stress Micro-Mirrors	137
B. Timotijevic, M. Tormen, R. Lockhart, M. Lutzelschwab, R. P. Stanley, F. Zamkotsian, P. Lanzoni, M. Canonica, W. Noell <i>Swiss Centre of Electronics and Microtechnology, SWITZERLAND</i> <i>Laboratoire d'Astrophysique de Marseille, FRANCE</i> <i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i>	
Convolution Spectrometer Demonstration using Programmable Diffraction Grating	139
F. Zamkotsian, P. Lanzoni, T. Viard <i>Laboratoire d'Astrophysique de Marseille, FRANCE</i> <i>Thales Alenia Space, FRANCE</i>	
Microtribometer Based on a Rotational Grating Displacement Sensing Mechanism	141
H. Yu, G. Zhou, F.S. Chau, S.K. Sinha, L. Jonathan Y. <i>National University of Singapore, SINGAPORE</i>	

Fabrication and Processing	143
Session Chair: Wilfried Noell	
<i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i>	
Monolithic Polymer Microlens Arrays with Anti-reflective Structures Using a Metal Annealed Mask	145
H. Jung, C. Song, K.-H. Jeong	
<i>Korea Advanced Institute of Science and Technology, KOREA</i>	
Fabrication of a Quasistatic-Resonant Microscanner by Implementing a Vertical Combdrive through Wafer Assembly Actuation	147
D. Kallweit, D. Jung, T. Sandner, H. Schenk	
<i>Fraunhofer Institute for Photonic Microsystems, GERMANY</i>	
A Deformable Mirror with Perforated Backplate for High-Speed Operation with Controlled Damping	149
M.J. Moghimi, K.N. Chattergoon, M.J. Strathman, C. Wilson, D.L. Dickensheets	
<i>Montana State University, USA</i>	
<i>Bridger Photonics Inc., USA</i>	
Cantilever Actuator Processing to Control Photoluminescence of Quantum Wells Coupled across Nanoscale Air Gaps	151
W.S. Chan, M.J. Saarinen, J.J. Talghader	
<i>University of Minnesota, USA</i>	
<i>Optoelectrics Research Centre, FINLAND</i>	
Development of CMOS MEMS Thermal Bimorph Actuator for Driving Microlens	153
K.H. Koh, C. Lee, J.-H. Lu, C.-C. Chen	
<i>National University of Singapore, SINGAPORE</i>	
<i>National Central University, TAIWAN</i>	
Vertical Flaps of Arbitrary Shape For Reflective MEMS Displays and Optical Modulators	155
F. Jutzi, W. Noell, N. F. de Rooij	
<i>Ecole Polytechnique Federale de Lausanne, SWITZERLAND</i>	
A Process for Fabricating Robust Electrothermal Micromirrors With Customizable Thermal Response Time and Power Consumption	157
S. Pal, H. Xie	
<i>University of Florida, USA</i>	
Posters	159
Integrating Microfluidic Sample Concentrator with Interferometric Reflectance Imaging Sensor for Point-of-care Viral Identification	161
J.Y. Zhang, G.G. Daaboul, J.H. Connor, S. Unlu, C.M. Klapperich	
<i>Boston University, USA</i>	

A Symmetric Hybrid MEMS Scanner with Electrothermal and Electrostatic Actuators	163
L. Li, R. Bauer, G. Brown, D. Uttamchandani <i>University of Strathclyde, UK</i>	
Near-Field Optical Transducer for Nanomechanical Resonators	165
O. Basarir, S. Bramhavar, K.L. Ekinici <i>Boston University, USA</i> <i>Ludwig-Maximilians-Universität, GERMANY</i>	
Measurement of the Taper Angle and X-ray Reflectivity of MEMS-based Silicon Mirrors	167
T. Ogawa, Y. Ezoe, Y. Kanamori I. Mitsuishi, K. Mitsuda, H. Yamaguchi, R. Riveros <i>Tokyo Metropolitan University, JAPAN</i> <i>Tohoku University, JAPAN</i> <i>ISAS/JAXA, JAPAN</i> <i>University of Florida, USA</i>	
Enhanced CF₄ Plasma Treated Polymer Film for Flexible Display Application	169
G. Tortissier, B. Kim, H. Fujita, H. Toshiyoshi, P. Ginet <i>University of Tokyo, JAPAN</i>	
A Robust, Non-Resonant Piezoelectric Micromirror	171
T. Bakke, I.-R. Johansen <i>SINTEF ICT, NORWAY</i>	
Whispering Gallery Modes Intrinsic Quality Factor and Coupling Regime Extraction Using Stokes Parameters	173
F. Vanier, C. La Mela, A. Hayat, Y.-A. Peter <i>Ecole Polytechnique de Montreal, CANADA</i>	
Fabrication and Evaluation of Polymer MEMS Mirror Based on the Mechanical Characteristic of Polymer Containing Magnetic Particles	175
T. Miura, T. Suzuki, K. Terao, H. Takao, F. Oohira <i>Kagawa University, JAPAN</i> <i>University of Hyogo, JAPAN</i>	
Beat Signal Transmission Through Whispering-Gallery-Mode Resonator	177
Y.L. Yu, M. Fukuhara, T. Aihara, K. Nakagawa, M. Fukuda, K. Yamaguchi <i>Toyohashi University of Technology, JAPAN</i> <i>Kagawa University, JAPAN</i>	
Selectively Thinned Stainless Steel Scanners Through Electrical Discharge Machining	179
B. Kucukakarsu Usta, Y.D. Gokdel, S. Mutlu, A.D. Yalcinkaya <i>Boğaziçi University, TURKEY</i>	

Three-Leaf Trefoil-Type MEMS Tunable Corner Cube Retro-Reflector	181
Y.-F. Chen, B.-J. Yang, Y.-J. Lin, K.-H. Chao, C.-C. Chang, J.-H. Huang, J.-C Tsai <i>National Taiwan University, TAIWAN</i>	
Design and Fabrication of Polymer MEMS Mirror Based on the Mechanical Characteristic Evaluation of Polyimide Materials	183
O. Sasaki, K. Terao, T. Suzuki, H. Takao, F. Oohira, Y. Kaibara, T. Namazu <i>Kagawa University, JAPAN</i> <i>University of Hyogo, JAPAN</i>	
Surface Profiling and Characterization of Microlenses Utilizing a Shack-Hartmann Wavefront Sensor	185
C. Li, G. Hall, B. Aldalali, D. Zhu, K. Eliceiri, H. Jiang <i>University of Wisconsin, USA</i>	
Hysteresis Comparison of Framed and Frameless Electrostatic X/Y Scanning Micromirrors	187
R. Bauer, G. Brown, D. Uttamchandani <i>University of Strathclyde, UK</i>	
Flip-Up Micro Scanning Mirror with Vertical Comb Drive Assembled by Simple Push Operations	189
C.-A. Chen, Y. Chiu <i>National Chiao Tung University, TAIWAN, R.O.C.</i>	
Fabry-Perot Fiber Sensors with Reproducible Displacement Sensitivities	191
O.C. Akkaya, O. Kilic, M.J.F. Digonnet, G.S. Kino, O. Solgaard <i>Stanford University, USA</i>	
An RF Front-End with Optically Powered CMOS Power Supply	193
B. Sarioglu, O. Aktan, U. Cindemir, S. Mutlu, G. Dundar, A.D. Yalcinkaya <i>Boğaziçi University, TURKEY</i>	
Laser Speckle Reduction by Using a Binary Micro Mirror Array (BMMA): Theory and Design	195
Z. Tong, X. Chen <i>Vestfold University College, NORWAY</i> <i>Norwegian University of Science and Technology, NORWAY</i>	
Simulation-based Study of A MEMS Wolter Type-I X-ray Telescope	197
Y. Ezoe, K. Ishizu, T. Moriyama, T. Ogawa, I. Mitsuishi, K. Mitsuda <i>Tokyo Metropolitan University, JAPAN</i> <i>Japan Aerospace Exploration Agency, JAPAN</i>	
Silicon Microsphere Based Filtering Application for Near-Infrared Optical Fiber Based Telecommunication	199
H. Yılmaz, U.S. Gökay, M.S. Tamer, O. Gürlü, A. Serpengüzel <i>Koç University, TURKEY</i>	

Particle Swarm Optimization on a New Parametric Model of a Deformable Membrane Lens	201
D. Strohmeier, J. Draheim, M. Domaszewski, A. Greiner, U. Wallrabe, J.G. Korvink <i>University of Freiburg, GERMANY</i> <i>University of Technology of Belfort-Montbéliard, FRANCE</i>	
Static and Dynamic Characterization of Poly-SiGe Grating Light Valves	203
S. Rudra, D. Van Thourhout, A. Witvrouw, J. De Coster, R. Van Hoof <i>Ghent University, BELGIUM</i> <i>IMEC, BELGIUM</i>	
Smoothing Sidewalls of A MEMS-based Silicon X-ray Optics	205
T. Moriyama, Y. Ezoe, T. Ogawa, T. Ohashi, Y. Kanamori, I. Mitsuishi, M. Mita, K. Mitsuda, A. Maeda <i>Tokyo Metropolitan University, JAPAN</i> <i>Tohoku University, JAPAN</i> <i>ISAS/JAXA, JAPAN</i> <i>Covalent Materials Corporation, JAPAN</i>	
Surface Plasmon Polariton-Enhanced Schottky-Type Photodetector	207
T. Aihara, K. Nakagawa, M. Fukuhara, Y.L. Yu, M. Fukuda, K. Yamaguchi <i>Toyohashi University of Technology, JAPAN</i> <i>Kagawa University, JAPAN</i>	
Transmission Color Control by Stacked Wire-Grid Polarizers with In-plane Rotation	209
A. Higo, T. Lee, S. Maruyama, H. Fujita, Y. Nakano, H. Toshiyoshi <i>University of Tokyo, JAPAN</i>	
Improvement in Light Emission of Si Nanocrystal LED using Surface Plasmons	211
C. Huh, B.K. Kim, W. Kim, J. Hong, S.H. Kim, B.-J. Park, E.H. Jang, K.-S. Shin, G.Y. Sung <i>ETRI, KOREA</i>	
Robustness Investigation of Nanoslit-based Plasmonic Lenses	213
Y. Yua, H. Zappe <i>University of Freiburg, GERMANY</i>	
Low-Loss Optical Switch using Brewster Angle	215
M. Kaykısız, E. Bulgan <i>Ozyegin University, TURKEY</i>	
Manipulating of Light Propagation Using Crescent- Shaped Photonic Crystals	217
M. Turduev, H. Kurt <i>TOBB University of Economics and Technology, TURKEY</i>	

Two-dimensional Quasi-Bessel Beam Creation	219
H. Kurt, M. Turdjev <i>TOBB University of Economics and Technology, TURKEY</i>	
Photonic Crystal Based Multi-Mode High-Q Cavity	221
A.E. Akosman, M. Mutlu, H. Kurt, E.Ozbay <i>Bilkent University, TURKEY</i> <i>TOBB University of Economics and Technology, TURKEY</i>	
Guidance Condition Correction into the Design of Two Dimensional Nanophotonic Devices	223
H. Gao, B. Zhang, S.G. Johnson, G. Barbastathis <i>Massachusetts Institute of Technology, USA</i> <i>Singapore-MIT Alliance for Research and Technology Centre, SINGAPORE</i>	
Velocity Estimation of Mobile Single Molecules for Improved Position Accuracy	225
M.Y. Yüce, A.T. Erdoğan, A. Kiraz <i>Koç University, TURKEY</i>	
Synthesis and Characterization of Cadmium Telluride Nanocrystals for Using Hybrid Solar Cell	227
J. Kim, H.T. Kim, C. Park <i>Yeungnam University, KOREA</i>	
A High-Throughput Biosensor for Detection and Quantification of Protein Induced DNA Bending	229
X. Zhang, P. Spuhler, M.S. Unlu, L. Sola, M. Chiari <i>Boston University, USA</i> <i>Istituto di Chimica del Riconoscimento Molecolare, ITALY</i>	
Multiplexed, Rapid, Point of Care Device to Quantify Allergen-Specific IgE	231
M.R. Monroe, A. Reddington, A. Collins, C. LaBoda, M. Cretich, M. Chiari, F. Little, M.S. Unlu <i>Boston University, USA</i> <i>Istituto di Chimica del Riconoscimento Molecolare, ITALY</i>	
Ultrasensitive Label-Free Microcavity Biosensors with High Selectivity	233
E. Ozgur, O. Aktas, M. Bayindir <i>Bilkent University, TURKEY</i>	
Fluorescence Detection System with Miniaturized Integrating Sphere	235
K. Kwon, B. Park, J. Shim, K. Yu <i>Korea Advanced Institute of Science and Technology, KOREA</i>	

Enhancing the Sensitivity of Dynamic Label-free Detection of Low Molecular Weight Protein 237

S. Ahn, D.S. Freedman, M.S. Unlu, M. Cabodi
Boston University, USA

Fabrication of Polydimethylsiloxane Microlens Arrays on Curved Surfaces 239

B. Aldalali, D. Zhu, H. Jiang
University of Wisconsin, USA